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LIST OF PATENTS AND
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APPLICANT BELLMAN ROBERT

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GROUP: 1756

REFERENCE DESIGNATION

U.S. PATENT DOCUMENTS

Examiner Initial		Document Number	Date	Name	Class	Sub-Class	Filing Date if Approp.
	AA	6,466,365	10/15/02	Maier et al.	359	355	
	AB	6,475,575	11/5/02	Ikuta et al.	428	14	
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						

FOREIGN PATENT DOCUMENTS

		Document Number	Date	Country	Class	Sub-Class	Translation Yes	No
	AL							
	AM							
	AN							

OTHER ART (Including Author, Title, Date, Pertinent Pages, etc.)

	AO	Jerry Cullins et al., 157 nm Photomask Handling and Infrastructure: Requirements and Feasibility, Proceedings of SPIE Vol. 4409 (2001) pages 632-640.
	AP	Eric P. Cotte et al., Dynamic Studies of Hard Pellicle Response During Exposure Scanning, J. Vac. Sci. Technol. B20(6), Nov/Dec 2002 pages 2995-2999.
	AQ	Encyclopedia of Chemical Technology, Volume 21, Recycling, Oil to Silicon, pages 750-763.
	AR	Andrew Grenville et al., International SEMATECH Hard Pellicle Task Force, July 3, 2002, pages 1-30.
	AS	Couillard et al., USSN 60/448,176, February 18, 2003, Glass-Based SOI Structures,
	AT	Encyclopedia of Chemical Technology, Liquid Crystalline Materials, Volume 15, Fourth Edition, pages 403-407.

EXAMINER:

DATE CONSIDERED:

8/5/05

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609: draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.